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PATENT APPLICATION  
ATTORNEY DOCKET NO. LMRX-P034/PI233

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: JAFARIAN-TEHRANI et al.  
Application No.: 10/816,211  
Filed: 3/31/2004

Title: METHODS AND ARRAY FOR CREATING A  
MATHEMATICAL MODEL OF A PLASMA  
PROCESSING SYSTEM

Examiner: UNKNOWN  
Group No.: 1763  
Confirmation No.: 7310

### CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the  
US Postal Service as First Class Mail in a postage-paid envelope  
addressed to the Commissioner for Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450 on April 26, 2005.

Signed: /Alma Fazlic/  
Alma Fazlic

### INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to the patentability of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§ 1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. If it is determined that fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-2284 (Order No. LMRX-P034).

Respectfully submitted,

By: /Joseph Nguyen/  
Joseph Nguyen  
Reg. No. 37,899



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**US PATENT DOCUMENTS**

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	Reference to Related Case

**OTHER DOCUMENTS**

Examiner Initials	Cite No.	Description	T
	I	STOUT et al., "Modeling Plasma Tools: Reactor and Feature Scales," pp. 1-6, <a href="http://www.google.com/search?q=cache:IPSVCEvzITsJ:cfplasma.trancetchno.com/vmic_2000.pdf+%22inductively+coupled+plasma%22+%22shower+head%22&amp;hl=en&amp;ie=UTF-8">http://www.google.com/search?q=cache:IPSVCEvzITsJ:cfplasma.trancetchno.com/vmic_2000.pdf+%22inductively+coupled+plasma%22+%22shower+head%22&amp;hl=en&amp;ie=UTF-8</a>	

Examiner Signature		Date Considered	
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